

CLAIMS

What is claimed is:

1. A manufacturing method for a liquid crystal display device, comprising the steps of:
applying a liquid crystal to a first substrate; and
bonding a second substrate to a surface of the first substrate to which the liquid crystal has been applied,
wherein a predetermined region of the second substrate is bonded to the first substrate, and the bonded region is expanded with the elapse of time.
2. The manufacturing method for a liquid crystal display device according to Claim 1, wherein
the predetermined region is pressed in the bonding step.
3. The manufacturing method for a liquid crystal display device according to Claim 1 or 2, wherein
the bonding step is carried out in an atmosphere of 2.7 k to 50 kPa.
4. The manufacturing method for a liquid crystal display device according to Claim 3, further comprising the steps of:
fixing the first substrate by a first vacuum chuck; and
fixing the second substrate by a second vacuum chuck.
5. The manufacturing method for a liquid crystal display device according to Claim 4, wherein
the second vacuum chuck comprises a plurality of retaining regions on a chuck surface thereof, the plurality of retaining regions being capable of performing mutually independent retaining operations and being disposed outward from the center of the chuck surface, and
the retaining operations of the plurality of retaining regions are stopped in order outward from the center in the bonding step.

6. The manufacturing method for a liquid crystal display device according to Claim 4, wherein the second vacuum chuck further comprises a holder that presses the second substrate, and the predetermined region is pressed by the holder in the bonding step. .

7. A bonding apparatus comprising:

a first vacuum chuck for fixing a first substrate; and

a second vacuum chuck that is positioned to oppose the first vacuum chuck and fixes a second substrate,

wherein the second vacuum chuck comprises a plurality of retaining regions on an chuck surface thereof, the plurality of retaining regions being capable of performing mutually independent retaining operations and being disposed outward from the center of the chuck surface, and

the second vacuum chuck stops the retaining operations of the plurality of retaining regions in order outward from the center.

8. The bonding apparatus according to Claim 7, wherein the second vacuum chuck further comprises a holder for pressing the second substrate.

9. The bonding apparatus according to Claim 8, wherein the holder has a curved contact surface.

10. The bonding apparatus according to Claim 8, wherein the holder has a plurality of contact surfaces.